L Number	Hits	Search Text	DB	Time stamp
1	507	250/\$.ccls. and ((scanning electron microscope) SEM) and auger	USPAT;	2004/08/05 07:59
			ЕРО; ЛРО;	
			DERWENT	
2	224	(250/\$.ccls. and ((scanning electron microscope) SEM) and auger) and	USPAT;	2004/08/05 07:45
		deflect\$5	ЕРО; ЈРО;	
			DERWENT	
3	76	((250/\$.ccls. and ((scanning electron microscope) SEM) and auger) and	USPAT;	2004/08/05 07:45
		deflect\$5) and objective adj lens	ЕРО; ЛРО;	
			DERWENT	~*
4	92	(250/\$.ccls. and ((scanning electron microscope) SEM) and auger) and	USPAT;	2004/08/05 08:00
		objective adj lens	ЕРО; ЛРО;	
		oojootivo aaj zonis	DERWENT	
_	1404	250/\$.ccls. and electron adj beam and optical adj system	USPAT;	2003/04/22 12:55
-	1404	250/\$.ccis. and electron and ocam and optical and system	ЕРО; ЛРО;	2003/04/22 12.33
	1.40	(0.50/0 1 1 1 4 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1	DERWENT	2002/04/22 07 57
-	142.		USPAT;	2003/04/23 07:57
		shield	ЕРО; ЈРО;	
			DERWENT	
-	9	((250/\$.ccls. and electron adj beam and optical adj system) and lens and	USPAT;	2002/12/12 09:58
		shield) and auger	ЕРО; ЛРО;	
			DERWENT	
•	3369	250/310-311.ccls.	USPAT;	2002/12/13 07:38
			ЕРО; ЛРО;	
			DERWENT	
_	120	250/310-311.ccls. and electron adj beam and lens and shield	USPAT;	2002/12/12 10:34
			ЕРО; ЛРО;	
			DERWENT	
_	107	(250/310-311.ccls. and electron adj beam and lens and shield) and	USPAT;	2002/12/13 07:38
-	107	microscope	ЕРО; ЛРО;	2002/12/13 07.38
		microscope	DERWENT	
	27	assendent odi electron and beelrogetten and detector and CEM		2002/12/12 12:42
-	27	secondary adj electron and backscatter and detector and SEM	USPAT;	2002/12/12 12:42
			EPO; JPO;	
		0.50.00.00.00.00.00.00.00.00.00.00.00.00	DERWENT	2002/12/12 12 55
-	404	250/310-311.ccls. and SEM	USPAT;	2002/12/12 12:57
			ЕРО; ЛРО;	
			DERWENT	
-	289	(250/310-311.ccls. and SEM) and secondary adj electron	USPAT;	2002/12/13 09:50
			EPO; JPO;	
			DERWENT	
-	9	("4789787" "4894549" "5182453" "5422486" "5436460"	USPAT	2002/12/12 14:51
		"5444243" "5510617" "6246058" "6259094").PN.		į
-	10	(250/310-311.ccls. and electron adj beam and lens and shield) and	USPAT;	2002/12/13 07:38
		microscope and capacitor	EPO; JPO;	
			DERWENT	
	20	(250/310-311.ccls. and SEM) and secondary adj electron and magnetic	USPAT;	2002/12/13 12:31
	-	adj pole	ЕРО; ЈРО;	
			DERWENT	
_	5	(250/310-311.ccls. and SEM) and auger and deflection adj plate	USPAT;	2002/12/13 12:34
-		250/510-511.0010. and 55501) and auger and defrection adj plate	EPO; JPO;	2002/12/13 12.34
	_	(250/210 211 colo and SEM) and nictual ali	DERWENT	2002/12/12 12:22
-	0	(250/310-311.ccls. and SEM) and virtual adj auger	USPAT;	2002/12/13 12:32
			EPO; JPO;	
			DERWENT	
-	39	(250/310-311.ccls. and SEM) and auger	USPAT;	2002/12/13 13:27
			ЕРО; ЈРО;	
			DERWENT	
-	3	("4126781").PN.	USPAT;	2002/12/13 13:27
			ЕРО; ЈРО;	
			DERWENT	
-	0	250/\$.ccls. and electron adi beam and optical adi system and dual adi		2002/12/13 14:21
-	0	250/\$.ccls. and electron adj beam and optical adj system and dual adj pole adj magnetic adj lens	USPAT; EPO; JPO;	2002/12/13 14:21

-	70	250/\$.ccls. and electron adj beam and optical adj system and magnetic adj pole	USPAT; EPO; JPO;	2002/12/13 15:42
1	*		DERWENT	
-	4	250/\$.ccls. and electron adj beam and optical adj system and spherical	USPAT;	2002/12/13 14:56
		adj capacitor	ЕРО; ЈРО;	
			DERWENT	
-	1	250/\$.ccls. and electron adj beam and optical adj system and	USPAT;	2002/12/13 14:57
		electrostatic adj capacitor	ЕРО; ЛРО;	
			DERWENT	
-	2	250/\$.ccls. and electron adj beam and optical adj system and	USPAT,	2002/12/13 14:57
		electrostatic adj detector	ЕРО; ЛРО;	
			DERWENT	
-	0	250/\$.ccls. and electron adj beam and optical adj system and duel adj	USPAT;	2002/12/13 15:43
		magnetic adj pole	ЕРО; ЈРО;	
			DERWENT	
-	6	(("4806754") or ("5770863")).PN.	USPAT;	2002/12/13 16:13
			ЕРО; ЈРО;	
			DERWENT	
-	21	scanning adj electron adj microscope and secondary adj electron and	USPAT;	2003/04/22 15:38
		lens and shield and capacitor	ЕРО; ЛРО;	
			DERWENT	
-	48	scanning adj electron adj microscope and auger adj electron and	USPAT;	2003/04/22 14:24
		deflect\$4 and analyz\$5	EPO; JPO;	
			DERWENT	
-	39	(scanning adj electron adj microscope and auger adj electron and	USPAT;	2003/04/22 13:25
		deflect\$4 and analyz\$5) and 250/\$.ccls.	ЕРО; ЛРО;	
			DERWENT	
-	10	((scanning adj electron adj microscope and auger adj electron and	USPAT;	2003/04/22 13:27
		deflect\$4 and analyz\$5) and 250/\$.ccls.) and shield	ЕРО; ЈРО;	
Ì			DERWENT	
-	0	(((scanning adj electron adj microscope and auger adj electron and	USPAT;	2003/04/22 13:27
		deflect\$4 and analyz\$5) and 250/\$.ccls.) and shield) and gradient	ЕРО; ЛРО;	'
		110,04	DERWENT	2002/04/22 12:20
-	13	scanning adj electron adj microscope and deflect\$4 and analyz\$5 and	USPAT;	2003/04/22 13:28
		shield and gradient	EPO; JPO;	
	108	scanning adj electron adj microscope and secondary adj electron and	DERWENT USPAT;	2003/04/22 14:11
-	108	lens and shield	EPO; JPO;	2003/04/22 14.11
		lens and sineid	DERWENT	
	18	(scanning adj electron adj microscope and secondary adj electron and	USPAT;	2003/04/22 14:12
	10	lens and shield) and auger	EPO; JPO;	2003/04/22 14.12
		icis and sincia) and dager	DERWENT	
_	10	scanning adj electron adj microscope and auger adj electron and	USPAT;	2003/04/22 16:38
		deflect\$4 and capacitor	ЕРО; ЛРО;	
		•	DERWENT	
-	680	scanning adj electron adj microscope and secondary adj electron and	USPAT;	2003/04/22 15:52
		resolution	ЕРО, ЛРО;	
	1		DERWENT	
-	437	(scanning adj electron adj microscope and secondary adj electron and	USPAT;	2003/04/22 15:39
		resolution) and 250/\$.ccls.	EPO; JPO;	
			DERWENT	
-	343	scanning adj electron adj microscope and secondary adj electron and	USPAT;	2003/04/22 15:53
-		resolution same beam and 250/\$.ccls.	EPO; JPO;	
			DERWENT	0000000000
-	247	scanning adj electron adj microscope and secondary adj electron and	USPAT;	2003/04/22 15:54
		resolution with beam and 250/\$.ccls.	EPO; JPO;	
1		and the same at the same at the same and the same at t	DERWENT	2002/04/22 16 22
-	98	scanning adj electron adj microscope and auger adj electron and	USPAT;	2003/04/22 16:38
		efficiency	EPO; JPO;	
	9	geographic adjulates and microscope and automatical states and	DERWENT	2003/04/22 16:20
-		scanning adj electron adj microscope and auger adj electron and collection adj efficiency	USPAT; EPO; JPO;	2003/04/22 16:39
		concetion any efficiency	DERWENT	
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-	16	250/\$.ccls. and electron adj beam and lens and shield and conductive	USPAT;	2003/04/23 08:18
		and resistive	ЕРО; ЛРО;	
			DERWENT	
-	151	250/\$.ccls. and electron adj beam and objective adj lens and shield	USPAT;	2003/04/23 08:49
			ЕРО; ЛРО;	
			DERWENT	
-	102	250/\$.ccls. and electron adj beam and objective adj lens and electrostatic	USPAT;	2003/04/23 08:26
		adj deflector	ЕРО; ЈРО;	
			DERWENT	
Ī -	23	250/\$.ccls. and electron adj beam and objective adj lens and electrostatic	USPAT;	2003/04/23 08:27
		adj deflector not magnetic	EPO; JPO;	
			DERWENT	
-	10	(250/\$.ccls. and electron adj beam and objective adj lens and	USPAT;	2003/04/23 08:27
		electrostatic adj deflector not magnetic) and secondary adj electron	ЕРО; ЛРО;	
		0.70/0	DERWENT	2002/04/22 10 40
-	20	250/\$.ccls. and electron adj beam and objective adj lens and deflector	USPAT;	2003/04/23 10:48
		and auger adj electron	ЕРО; ЛРО;	
		250/6 1 114 111 11 110 4 1 11	DERWENT	2002/04/22 10 41
-	6	250/\$.ccls. and electron adj beam and lens and deflector and auger adj	USPAT;	2003/04/23 10:41
		electron and capacitor	EPO; JPO; DERWENT	
	19	250/\$ calc. and electron adi beam and objective adi long and deflector	USPAT:	2003/04/23 10:48
_	19	250/\$.ccls. and electron adj beam and objective adj lens and deflector	,	2003/04/23 10:48
		and auger adj electron and image	ЕРО; ЛРО;	
	l		DERWENT	